

Ceramic Susceptor and Semiconductor or Liquid-Crystal Manufacturing Apparatus in Which the Susceptor Is Installed

Abstract

Ceramic susceptor having a processed-object retaining face—and semiconductor as well as liquid-crystal manufacturing apparatuses in which the susceptor is installed—in which temperature uniformity in the surface of an object being processed on the susceptor is enhanced. Forming a resistive heating element in the susceptor surface on other than its processed-object retaining side, or on an internal surface of the susceptor, and forming a lead circuit for supplying electricity to the resistive heating element in a surface separate from the surface on which the resistive heating element is formed, allows the temperature uniformity of the susceptor to be enhanced and enables uniformization of the temperature distribution in the processed-object retaining face.